

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Seong Deok Ahn et al.

Application No.: 10/672,013

Filed: September 26, 2003

For: **Method and Apparatus Using Large-Area
Organic Vapor Deposition for Formation of
Organic Thin Films or Organic Devices**

Examiner: Richard R. Bueker

Art Unit: 1792

Confirmation No.: 7684

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AMENDMENT AND RESPONSE TO FINAL OFFICE ACTION

In response to the Final Office Action mailed June 20, 2008, in connection with the above referenced patent application, Applicants respectfully request entry of the following amendments and request reconsideration in view of the following remarks.

Amendments to the claims begin on page 2.

Remarks begin on page 6.